

Form PTO-1449 (MODIFIED)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. 39153/325 (F0853)		SERIAL NO. Unknown			
INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>				APPLICANT Babcock et al.		<div style="text-align: right;"> J1050 U.S. PTO 10/04/03 </div>			
				FILING DATE Unknown				GROUP ART UNIT Unknown	
U.S. PATENT DOCUMENTS									
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE		
FOREIGN PATENT DOCUMENTS									
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION YES NO		
OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>									
		Douglas Van Den Broeke, Transferring Phase-Shifting Mask Technology into Mainstream Manufacturing, printed from Internet address: http://www.semiconductorfabtech.com/f...s/lithography/articles/body5.225.php3 on October 6, 2000, 7 pages							
				Andrew B. Kahng et al., Subwavelength Lithography and its Potential Impact on Design and EDA, 6 pages					
EXAMINER		DATE CONSIDERED							
* EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include any copy of this form with next communication to applicant.									